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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Smith, *et al.* Docket No.: 2001 P 11900 US01
Serial No.: 10/786,996 Art Unit: 1746
Filed: February 25, 2004 Examiner: Alexander Markoff
For: Method of Removing PECVD Residues of Fluorinated Plasma Using In-Situ H₂ Plasma

Certificate of Mailing via First Class Mail (37 C.F.R. § 1.8(a))

Date of Deposit: January 20, 2006

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Information Disclosure Statement (1 original and 1 copy)
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Respectfully submitted,

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